

## AMENDMENT TRANSMITTAL LETTER

Docket No.  
M4065.0073/P073

Serial No. 09/123,430	Filing Date July 28, 1998	Examiner B. Kebede	Group Art Unit 2823
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Applicant(s): Donald L. Yates

Invention: METHOD OF REDUCING SURFACE CONTAMINATION IN SEMICONDUCTOR WET-PROCESSING VESSELS

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## TO THE ASSISTANT COMMISSIONER FOR PATENTS

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

## CLAIMS AS AMENDED

	Claims Remaining After Amendment	Highest # Previously Paid	# Extra Claims Present	Rate	Additional F e
<b>Total Claims</b>	28	- 47 =	0	x \$18.00	
<b>Independent Claims</b>	14	- 8 =	6	x \$80.00	\$480.00
<b>Multiple Dependent Claims (check if applicable)</b> <input type="checkbox"/>					
<b>Other fee (please specify):</b>					
<b>TOTAL ADDITIONAL FEE FOR THIS AMENDMENT</b>					\$480.00

 Large Entity Small Entity No additional fee is required for amendment. Please charge Deposit Account No. 4 - 1073 in the amount of \_\_\_\_\_  
A duplicate copy of this sheet is enclosed. A check in the amount of \_\_\_\_\_ \$480.00 to cover the filing fee is enclosed. The Commissioner is hereby authorized to charge and credit Deposit Account No. 4 - 1073 as described below. A duplicate copy of this sheet is enclosed. Credit any overpayment. Charge any additional filing or application processing fees required under 37 C.F.R. 1.16 and 1.17.

Dated: October 4, 2000

Thomas J. D'Amico

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PATENT  
Docket No.: M4065.0073/P073

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Donald Yates

Serial No.: 09/123,430

Group Art Unit: 2823

Filed: July 28, 1998

Examiner: B. Kebede

For: METHOD OF REDUCING  
SURFACE CONTAMINATION IN  
SEMICONDUCTOR WET-  
PROCESSING VESSELS

Assistant Commissioner for Patents  
Washington, D.C. 20231

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AMENDMENT UNDER 37 C.F.R. § 1.116

Dear Sir:

In response to the Office Action dated July 5, 2000 (Paper No. 10), finally rejecting claims 1-10, 14-17, 20, 24, 26 and 27, please amend the above-identified U.S. patent application as follows:

IN THE CLAIMS:

Please cancel claims 28-43 and 45-47.

10/06/2000 AWONDAF1 00000072 09123430

Please amend the following claims: 01 FC:102

480.00 0P

1. (twice amended) A method for removing contaminants from a semiconductor processing bath for processing semiconductor wafers, said method comprising: